

Lang und Peitler automates exhaust scrubbers with SEMI standard F97-compliant interfaces performed by Siemens PLC solutions

# Cleaning on a high standard

Every chip factory is equipped with a wide variety of scrubbers and gas supply systems that are typically equipped with their own autonomous controllers and, when possible, with separate operator controls. This makes it possible for systems to be modularly copied and expanded during operation while restricting malfunctions to a single system.

**A**s a subsidiary of M+W Zander Group and the world market leader in the planning and construction of chip factories, Lang und Peitler automates exhaust gas washers equipped with an interface for integration of the Facility Monitoring and Control System (FMCS) in accordance with the latest SEMI standard F97.

## Integration to F97

The F97 standard specifies the requirements for the architecture, common services, data and their semantic meaning for integrating facility package units (e.g. chemicals, cooling system, power supply, access control) in the FMCS. The tools, while autonomous, can also be externally controlled over an FMCS as circumstances dictate. Here, they are visualized at a central location and re-enabled following a general shutdown.

The use of components from the Siemens Simatic product family, as well as the application of SEMI standard F97, makes subsequent integration in the FMCS PCS 7 from Siemens possible requiring minimum overhead and ensures the uniformity of HMI operator interfaces. The systems nor-



mally run in automatic mode, but also offer a simple, self-explanatory, well-structured operator control system so that operating personnel can respond rapidly and efficiently in the event of a problem. Their modular design also has advantages when the systems are integrated in a life safety system.

## Sophisticated components from the Siemens product family

Controllers from the S7-300 series from Siemens have access to a sophisticated library of software blocks with standardized functionalities tailored specifically to the semiconductor industry. Additionally, the Siemens OP 77B Operator Panel as well as Panels OP 170B to MP 370 are used for operator control and monitoring. Since some equipment data, such as differential scrubber pressure and pressures and temperatures of the gases, represent quality-relevant process variables, they are also made available to the monitoring systems by Lang und Peitler via ToolLink from the S7-300 over SECS2. ■

## Lang und Peitler Automation GmbH

Lang und Peitler Automation GmbH, headquartered in Ludwigshafen/Rhein, is one of the leading vendor-independent suppliers of all-in-one automation solutions for the process and manufacturing industries. Services include everything from consulting and planning to commissioning and subsequent support. The company's main focus is on the creation of software for FMCS.

**More information about Lang und Peitler:** [www.langundpeitler.de](http://www.langundpeitler.de)



Lang und Peitler Automation GmbH is a 100% subsidiary of M+W Zander Facility Engineering GmbH, where it represents the independent "Automation" business segment.

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